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) December 19, 2002
) (Date)

Michael H. Trenholm, Reg. No. 37,743

#11/B
4-16-03
afx

Dear Sir:

In response to the Office Action mailed on June 19, 2002 (Paper No. 9), the Applicant respectfully requests amendment of the above-captioned application as follows:

Please amend the Claims as follows:

9. (Twice Amended) The process of Claim 6, wherein the step of replacing the silicon in the silicon electrode structure comprises forming a boundary layer on the silicon electrode structure, exposing the silicon electrode structure to a refractory metal-halide complex, and removing the boundary layer.

10. (Twice Amended) The process of Claim 9, wherein the boundary layer comprises a dielectric and the refractory metal-halide complex comprises WF_6 .